# More-than-Moore 3D Integration With Low Thermal Budget

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#### Introduction

## Background

- 3D integration provides accommodation of more transistors on the same footprint without the need to shrink transistor sizes.
- Controlled thermal budget is the key to vertical integration of multifunctional devices without performance degradation.

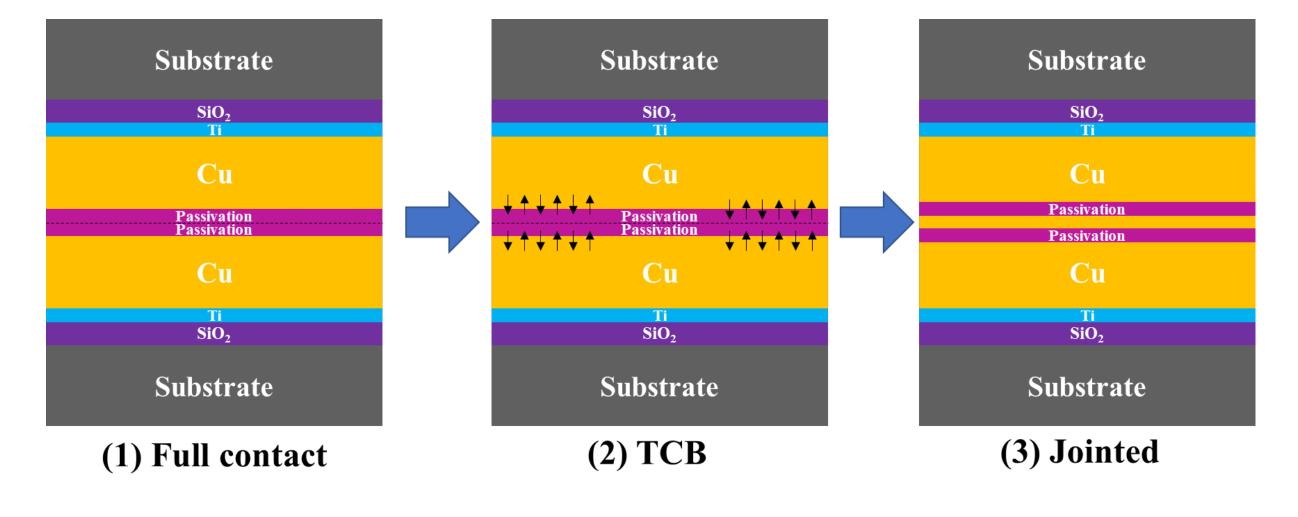
## Accomplishments

- Passivated-Cu/SiO<sub>2</sub> hybrid bonding was developed for chip stacking with low thermal budget (120 °C, 1 min).
- Location-controlled-grain (LCG) technique was developed to realize monolithic 3DIC with controlled thermal budget.

| Attribute           | Cu/SiO <sub>2</sub> Hybrid Bonding | Monolithic 3D            |
|---------------------|------------------------------------|--------------------------|
| Channel Quality     | Higher                             | Lower                    |
| Stacking Thickness  | Thicker                            | Thinner                  |
| Alignment Precision | Lower                              | Higher                   |
| Applicability       | Higher                             | Lower                    |
| Target I/O Pitch    | 1-10 μm                            | < 1 μm                   |
| Thermal Challenges  | Bonding temperature                | Process for active tiers |

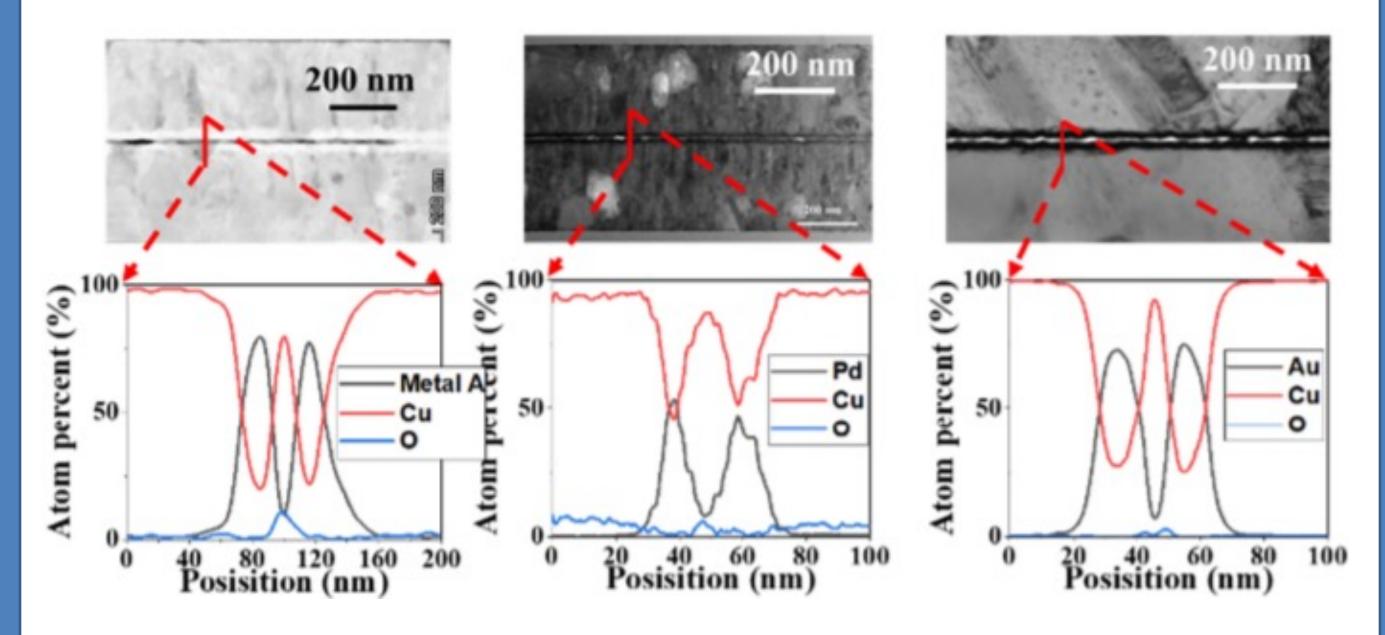
## Passivated-Cu/SiO<sub>2</sub> Hybrid Bonding

## Mechanism of passivated-Cu bonding



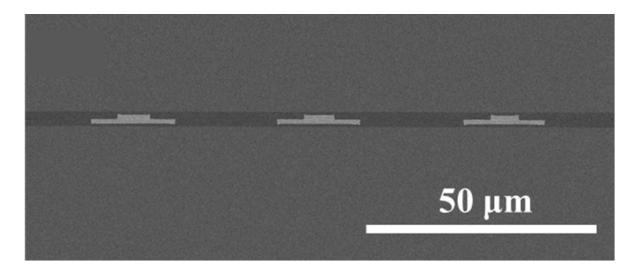
- Candidates of passivation includes 10 nm Au, Pd, or Ag.
- Cu can diffuse through passivation to achieve Cu-Cu bonding

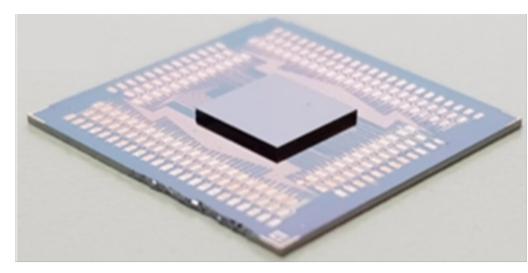
#### Analyses of passivated-Cu bonding at 150 °C

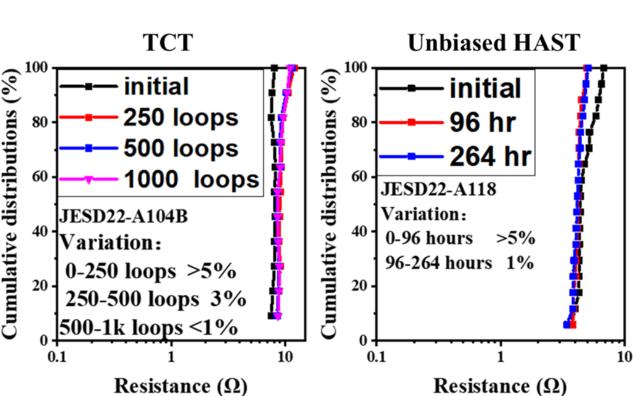


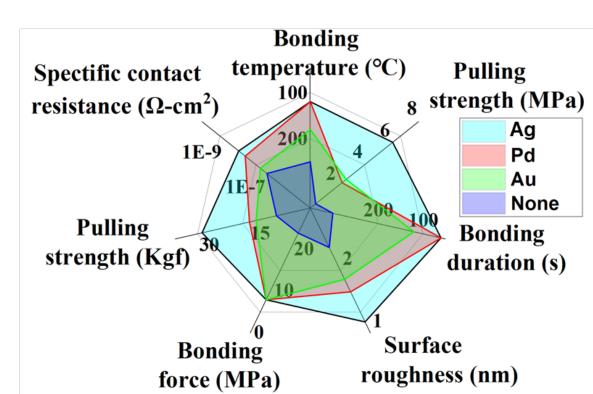
• Passivated-Cu bonding at 150 °C was demonstrated and analyzed by SEM, TEM, and EDX.

## Low temperature passivated-Cu/SiO<sub>2</sub> hybrid bonding





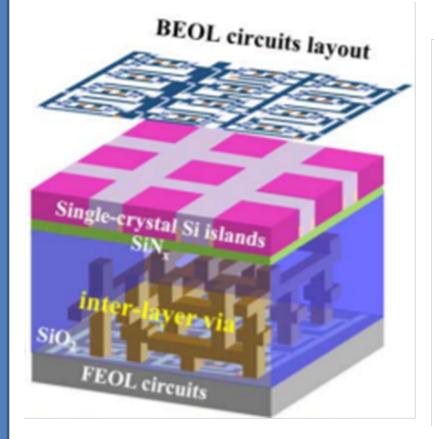


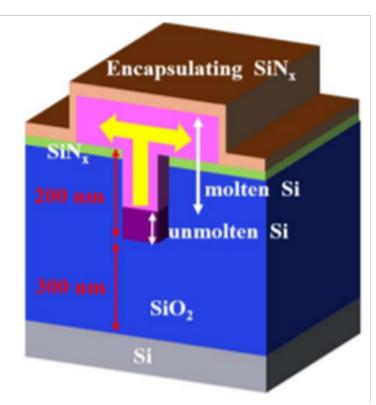


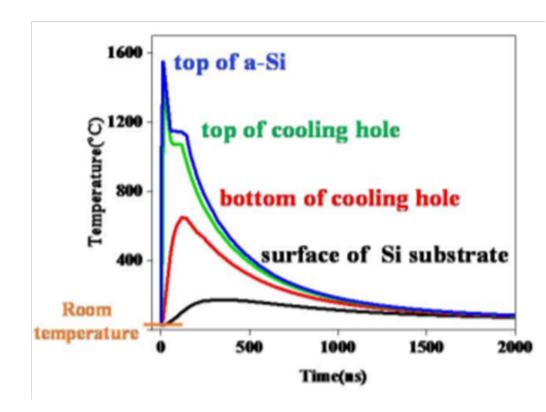
• Passivated-Cu/SiO<sub>2</sub> hybrid bonding can be achieved with low thermal budget (120 °C, 1 min) and excellent reliability.

#### Monolithic 3DIC based on LCG technique

## Controlled thermal budget using LCG technique

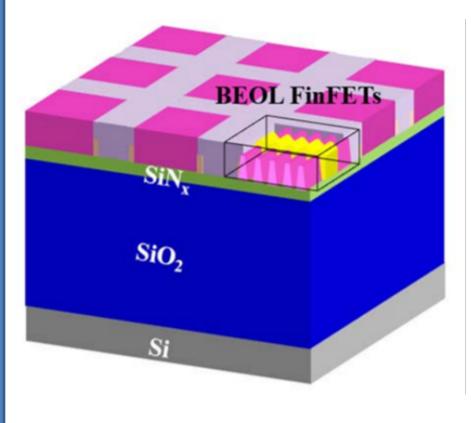


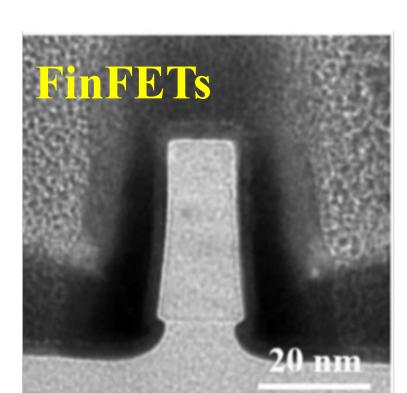


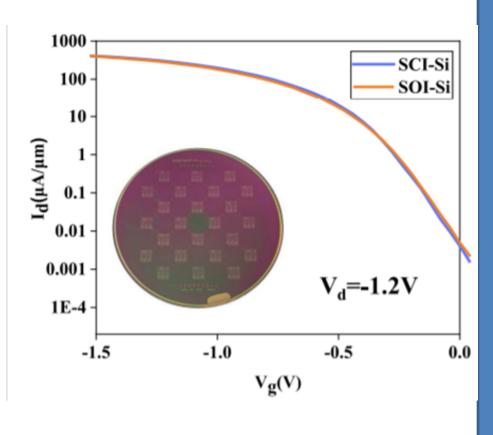


• Based on LCG, single-crystal Si islands were achieve, and the temperature of bottom layers can maintain lower than 200 °C.

## Single-crystal Si islands for fabrication of FinFETs







• For single-crystal Si islands, the random grain-boundary effect can be prevented to provide high performance FinFETs.

#### Conclusions

- Advanced 3D integration technologies with low thermal budget were developed, including passivated-Cu/SiO<sub>2</sub> hybrid bonding and LCG-based monolithic 3DIC.
- Our recent 3D integration: 2019 IEDM, 2020 IEDM, and 2020 VLSI.
- LCG-based monolithic 3DIC for Ge FinFETS will be published in 2021 IEDM.



